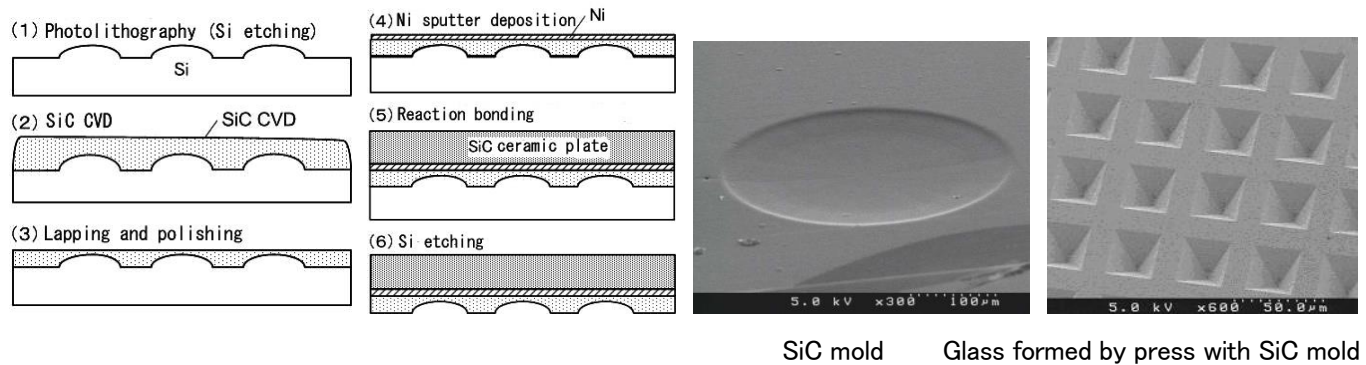
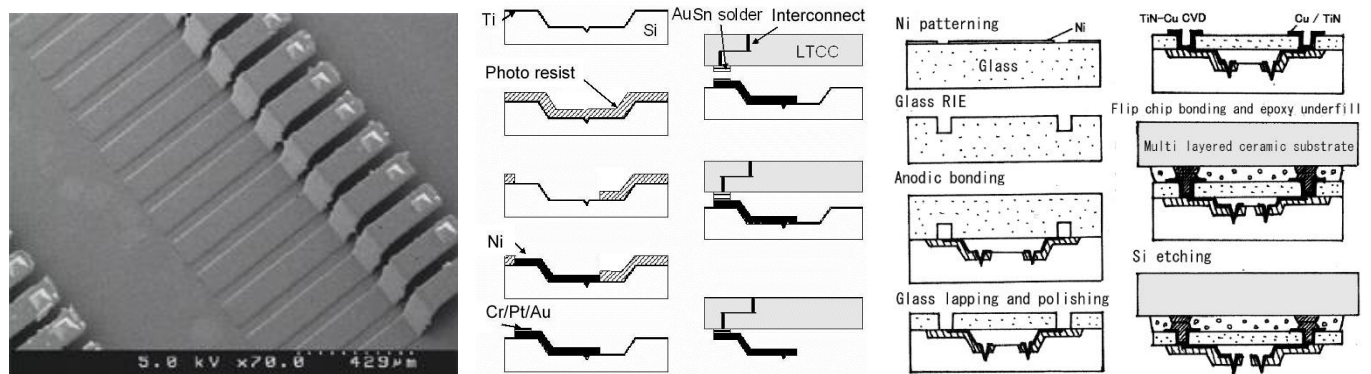


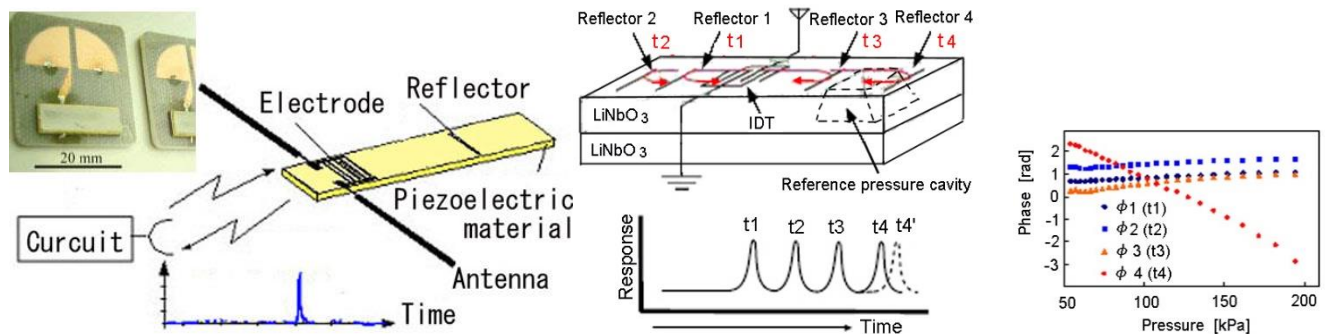
MEMS for production, testing, environment and safety (S.Tanaka, M.Esashi et.al.)



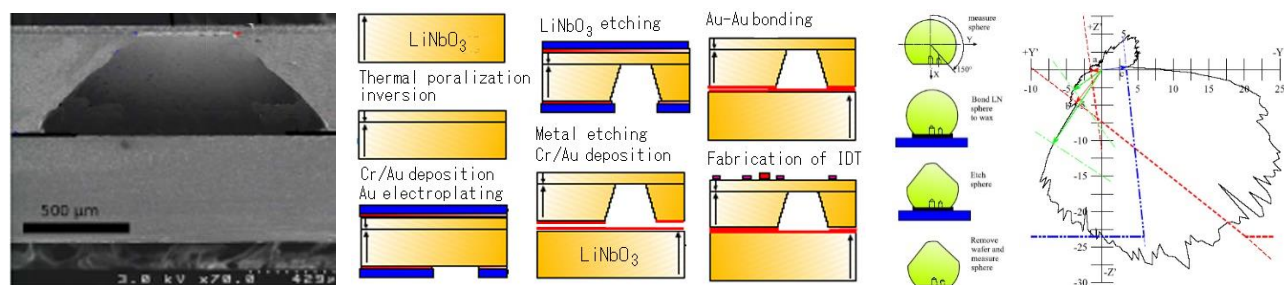
SiC mold for glass press molding (T. Itoh, J. of Microelectromechanical Systems, 15 (2006) 859)



Probe card for testing LSI wafer (S. -H. Choe et. al., IEEE Internl. Test Conf. 2007 (2007))



Surface Acoustic Wave (SAW) wireless passive sensor. Tire pressure monitoring system and its LiNbO₃ diaphragm (S.Hashimoto et.al (Nissan motor), Transaction of IEEJ, 128-E (2008) 231)



LiNbO₃ diaphragm and its fabrication process using thermal polarization inversion and anisotropic etching

(A.B.Randles et.al, Jap. J. of Applied Physics, 46,45 (2007) L1099-1101)

(A.B.Randles et.al, IEEE Trans. on Ultrasonics, Ferroelectrics, and Frequency Control, 57, 11 (2010) 2372-2380)

Anisotropic etching of LiNbO₃ depending on crystal orientation.